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Dated: September 11, 2001

Signature: 

(Marcus J. Millet)

Docket No.: TESSERA 3.0-085 CONT DIV CIP DIV
(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:
Joseph Fjelstad

Application No.: 09/732,821

Group Art Unit: 2812

Filed: December 7, 2000

Examiner: J. Kennedy

For: METHODS FOR MANUFACTURING
RESISTORS USING A SACRIFICIAL
LAYER

Commissioner for Patents
Washington, DC 20231

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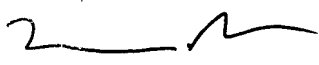
RESPONSE

Dear Sir:

The present communication is responsive to the restriction requirement mailed July 3, 2001.

In response to the restriction requirement, applicant hereby elects the claims of Group I, namely claims 1-42 for prosecution in the present application.

Dated: September 11, 2001 Respectfully submitted,

By 

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